

U.S. Department of Commerce, Patent and Trademark Office	Application No.:	09/788,273
	Filing Date:	Feb. 16, 2001
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	First Named Inventor:	Jiping Li
(Use several sheets if necessary)	Group Art Unit:	2823
	Examiner Name:	Michelle Estrada
	Confirmation No.:	6335
	Attorney Docket No.:	BOX009 US

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
ME	AA	4,710,030	12/1987	Tauc et al.	356	445	
ME	AB	4,521,118	6/1985	Rosencwaig	374	5	
ME	AC	5,978,074	11/1999	Opsal et al.	356	72	

Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
ME	AD	JP 2000009443A	01/2000	Japan	G01B	11/24	X	
ME	AE	0 718 595	6/1996	Europe	G01B	11/06		X

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

ME	AF	Bristow, Thomas C. and Dag Lindquist, "Surface Measurements With A Non-Contact Nomarski-Profilng Instrument", Interferometric Metrology, SPIE vol. 816, August 1987, pages 106-110
ME	AG	Walter G. Driscoll and William Vaughan, "Handbook of Optics", 1978, pages 8-42, 8-43, 8-107, and 10-72 to 10-77
ME	AH	Charles Kittel, "Introduction to Solid State Physics", Fourth Edition, John Wiley & Sons, published prior to March 1, 2002, pages 262-264
ME	AI	Rolf E. Hummel, "Electronic Properties of Materials, An Introduction For Engineers", published prior to March 1, 2002, pages 137-145
ME	AJ	H.S. Carslaw and J.C. Jaeger, "Conduction of Heat In Solids", Second Edition, published prior to March 1, 2002, pages 64-66
ME	AK	"Process Monitoring System", Quantox Product Brochure, 3 pages, published prior to March 1, 2002
ME	AL	S. Wolf and R. N. Tauber, "Silicon Processing For The VLSI Era", Volumn 1, 1986, pages 388-399
ME	AM	Yaozhi Hu and Sing Pin Tay, "Spectroscopic ellipsometry investigation of nickel silicide formation by rapid thermal process", J. Vac. Sci. Technology, American Vacuum Soc. May/Jun 1998, pages 1820-1824
ME	AN	Dieter K. Schroder "Semiconductor Material And Device Characterization", John Wiley & Sons, Inc. 1990, pages 538-561, and 458-466
ME	AO	Quality Today News, article entitled "In-Line Metrology SEM System with 3D Imaging" dated January 10, 2000 and published at http://www.qualitytoday.com/Jan-00-news/011000-3.htm before April 4, 2001

Examiner Michelle Estrada Date Considered9/23/03

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ME	AP	4,273,421	6/1981	Gurtler	356	432	
ME	AQ	6,169,601	1/2001	Eremin et al.	356	239.8	
ME	AR	5,966,019	10/1999	Borden	324	752	
ME	AS	5,377,006	12/1994	Nakata	356	349	
ME	AT	5,706,094	1/1998	Maris	356	432	
ME	AU	6,118,533	9/2000	Banet et al.	356	345	
ME	AV	6,323,951	11/2001	Borden et al.	356	502	
ME	AW	6,426,644	7/2002	Borden et al.	324	765	
ME	AX	6,489,801	12/2002	Borden et al.	324	766	
ME	AY	4,996,659	2/1991	Yamaguchi et al.	364	579	
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ME	BA	5,761,082	6/1998	Miura-Mattausch	364	490	
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ME	BC	5,379,109	01/1995	Gaskill et al.	356	445	
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ME	BE	5,667,300	9/1997	Mandelis et al.	374	43	
ME	BF	5,764,363	6/1998	Ooki et al.	356	364	
ME	BG	5,790,251	8/1998	Hagiwara	356	351	
ME	BH	5,228,776	7/1993	Smith et al.	374	5	
ME	BI	5,304,931	4/1994	Flamig et al.	324	309	
ME	BJ	5,128,864	7/1992	Waggner et al.	364	413.21	
ME	BK	6,178,020	1/2001	Schultz et al.	359	107	
ME	BL	4,201,087	5/1980	Akita et al.	73	339	
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<i>ME</i>	BO	3,803,413	4/1974	Vanzetti et al.	250	338	
<i>ME</i>	BP	4,255,971	3/1981	Rosenowig	73	606	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>ME</i>	BQ	"Calibration As Well As Measurement On The Same Workpiece During Fabrication" by Peter G. Borden, Jiping Li and Jon Madsen, US Application 09/974,571, filed October 9, 2001, Atty Docket BOX013
<i>ME</i>	BR	"Identifying Defects In a Conductive Structure Of A Wafer, Based On Heat Transfer Therethrough" by Peter G. Borden and Jiping Li, US Application 10/090,287, filed March 1, 2002, Atty Docket BOX014
<i>ME</i>	BS	Office Action dated March 26, 2003 in US Application 10/090,287
<i>ME</i>	BT	"Measurement of Lateral Diffusion of Diffused Layers" by Peter G. Borden, G. Jonathan Kluth and Eric Paton, US Application 10/253,121, filed September 23, 2002, Atty Docket BOX010
<i>ME</i>	BU	Office Action dated July 2, 2002 in US Application 09/521,232
<i>ME</i>	BV	Response to Office Action dated August 20, 2002 in US Application 09/521,232
<i>ME</i>	BW	Office Action dated December 19, 2002 in US Application 09/521,232
<i>ME</i>	BX	Response to Office Action dated May 19, 2003 in US Application 09/521,232
<i>ME</i>	BY	"Evaluating A Multi-layered Structure For Voids" by Peter G. Borden and Jiping Li, US Application 10/090,262 filed March 1, 2002, Atty Docket BOX012
<i>ME</i>	BZ	Office Action dated March 4, 2003 in US Application 10/090,262
<i>ME</i>	CA	Response to Office Action dated May 5, 2003 in US Application 10/090,262
<i>ME</i>	CB	Office Action dated May 23, 2003 in US Application 10/090,262
<i>ME</i>	CC	"An Apparatus and Method For Measuring A Property Of A Layer In A Multilayered Structure" by Peter G. Borden and Jiping Li, US Application 10/090,316 filed March 1, 2002, Atty Docket BOX006
<i>ME</i>	CD	"Measurement of Lateral Diffusion of Diffused Layers" by Peter G. Borden, US Application 10/253,119, filed September 23, 2002, Atty Docket BOX015

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